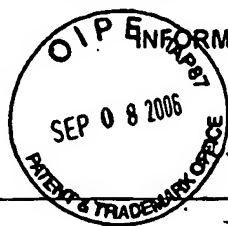


FORM PTO-1449



INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(Use several sheets if necessary)

Docket Number (Optional)
KLAC0075Application No.
10/615,512Applicant
Yung-Ho Chuang, et al.Filing Date
July 7, 2003Group Art Unit
2872

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
LF	2	6	6	1	6	5	8	12/1953	Dyson			
	1	9	7	3	0	6	6	9/1934	Hauser et al.			
	4	9	7	4	0	9	4	11/1990	Morito			
	4	7	5	8	0	8	8	7/1988 7/19/1988	Doyle			
	5	1	7	7	5	5	9	1/1993	Batchelder et al.			
	4	8	9	8	4	7	1	2/1990	Stenstrom et al. Vaught, et al.			
	5	4	2	8	4	4	2	6/1995	Lin et al.			
	5	0	3	1	9	7	6	7/1991	Shafer			
	5	7	1	7	5	1	8	2/1998	Shafer et al.			
	5	6	4	4	1	4	0	7/1997	Biedermann et al.			
	5	4	8	8	2	2	9	1/1996	Elliott et al.			
	3	2	3	7	5	1	5	3/1966	Altman			
LF	5	7	1	7	5	1	8	2/1998	Chuang			

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	Translation	
												Yes	No
LF	3	7	4	2	8	0	6	7/1989	DE				
LF	9	7	1	2	2	2	6	4/1997	WO				
LF	1	0	8	1	8	1		1/1900	DE				
LF	2	2	6	9	0	2	4	1/1994	GB				
LF	0	7	9	8	5	8	5	10/1997	EP				

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

LF	M.R. Bartz et al., "LED Print Analyzer," IBM Technical Disclosure Bulletin, Vol 14, No. 3, 8/1971
LF	D.S. Goodman, "Darkfield Illuminator Attachment," IBM Technical Disclosure Bulletin, Vol. 27, No. 5, 10/1984
LF	J.L.C. Sanz et al., "Automated Visual Inspection with Dark-Field Microscopy," Journal of the Optical Society of America, November 1985, USA, Vol. 2, No. 11, pp. 1857-1862
LF	Carl Zeiss Brochure, "MSM 193 Microlithography Simulation Microscope," 1999

EXAMINER

/Lee Fineman/

DATE CONSIDERED

10/30/2006

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP §609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.